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**Nanotechnologies — Characterization  
of multiwall carbon nanotubes —  
Mesoscopic shape factors**

*Nanotechnologies — Caractérisation des nanotubes en carbone  
multicouches — Facteurs de forme mésoscopique*

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## Foreword

ISO (the International Organization for Standardization) is a worldwide federation of national standards bodies (ISO member bodies). The work of preparing International Standards is normally carried out through ISO technical committees. Each member body interested in a subject for which a technical committee has been established has the right to be represented on that committee. International organizations, governmental and non-governmental, in liaison with ISO, also take part in the work. ISO collaborates closely with the International Electrotechnical Commission (IEC) on all matters of electrotechnical standardization.

The procedures used to develop this document and those intended for its further maintenance are described in the ISO/IEC Directives, Part 1. In particular the different approval criteria needed for the different types of ISO documents should be noted. This document was drafted in accordance with the editorial rules of the ISO/IEC Directives, Part 2 (see [www.iso.org/directives](http://www.iso.org/directives)).

Attention is drawn to the possibility that some of the elements of this document may be the subject of patent rights. ISO shall not be held responsible for identifying any or all such patent rights. Details of any patent rights identified during the development of the document will be in the Introduction and/or on the ISO list of patent declarations received (see [www.iso.org/patents](http://www.iso.org/patents)).

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For an explanation on the voluntary nature of standards, the meaning of ISO specific terms and expressions related to conformity assessment, as well as information about ISO's adherence to the World Trade Organization (WTO) principles in the Technical Barriers to Trade (TBT) see the following URL: [www.iso.org/iso/foreword.html](http://www.iso.org/iso/foreword.html). (standards.iteh.ai)

This document was prepared by Technical Committee ISO/TC 229, *Nanotechnologies*.

This second edition cancels and replaces the first edition (ISO/TS 11888:2011), which has been technically revised.

## Introduction

Multiwall carbon nanotubes (MWCNTs) synthesized by chemical vapour deposition (CVD) are of growing interest for use in polymer composites and conductive coatings. In many cases, MWCNTs synthesized by CVD have static (permanent) bend points randomly distributed along their axis. Physical and chemical properties of mass-produced MWCNTs are strongly dependent on the statistical distribution of mesoscopic shapes and sizes of the individual MWCNT (see ISO/TS 80004-3), among other parameters, that comprise the product.<sup>[4][6]</sup> It is therefore crucial to characterize the mesoscopic shapes of MWCNTs in order to ensure that the final properties are reproducible for use in a wide range of materials, including composites and other dispersions, as well as for Environment, Health and Safety (EHS) issues.<sup>[7]</sup>

This document provides methods for the characterization of mesoscopic shape factors of MWCNTs, including sample preparation procedures. In particular, it provides a statistical method for characterizing MWCNTs produced by the CVD method. During MWCNT synthesis, axial structures are not perfectly linear but include static bend points.

This document provides methods for determining a statistical quantity, representing a maximum straight length that is not deformed by permanent bending called the “static bending persistence length” (SBPL). The SBPL gives information regarding the relationship between the MWCNT mesoscopic shape and size. If two MWCNTs of equal length have different SBPLs, their overall sizes (e.g. radius of gyration or an equivalent diameter such as a hydrodynamic diameter) will also be different from one another. In practical applications, the variation in SBPL affects both chemical reactivity and physical properties.<sup>[4][5][6]</sup>

Electrical conductivity and dimensional stability of MWCNT-polymer compounds are also strongly dependent on the SBPL of the MWCNT used to make them.<sup>[4][5][6]</sup> Various properties might be affected by SBPL, including electrical percolation threshold,<sup>[6][8]</sup> toxicity,<sup>[7]</sup> thermal conductivity,<sup>[9]</sup> rheological property<sup>[10]</sup> and field emission property.<sup>[11]</sup> SBPL could be useful for estimating the loading of a MWCNT-polymer matrix to achieve electrical conductivity (percolation limit) and should also assist with modelling the mechanical properties of MWCNT-polymer composites with different loadings.

Prior to commencing any work, users are advised to familiarize themselves with the latest guidance on handling and disposal of MWCNTs, particularly in relation to the use of appropriate personal protective equipment. Information on current practices is available in ISO/TR 12885.

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# Nanotechnologies — Characterization of multiwall carbon nanotubes — Mesoscopic shape factors

## 1 Scope

This document describes methods for the characterization of mesoscopic shape factors of multiwall carbon nanotubes (MWCNTs). Techniques employed include scanning electron microscopy (SEM), transmission electron microscopy (TEM), viscometry, and light scattering analysis.

This document also includes additional terms needed to define the characterization of static bending persistence length (SBPL). Measurement methods are given for the evaluation of SBPL, which generally varies from several tens of nanometres to several hundred micrometres.

Well-established concepts and mathematical expressions, analogous to polymer physics, are utilized for the definition of mesoscopic shape factors of MWCNTs.

## 2 Normative references

There are no normative references in this document.

## 3 Terms, definitions and abbreviated terms

### 3.1 Terms and definitions

For the purposes of this document, the following terms, definitions and abbreviated terms apply.

ISO and IEC maintain terminological databases for use in standardization at the following addresses:

- ISO Online browsing platform: available at <http://www.iso.org/obp>
- IEC Electropedia: available at <http://www.electropedia.org/>

NOTE Formulae for some of these terms and definitions are given in [Annex A](#).

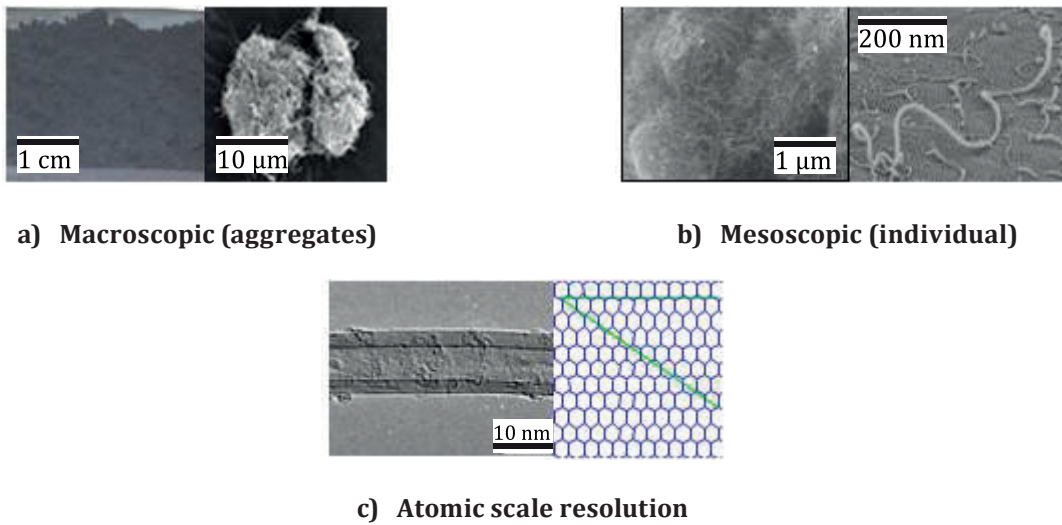
#### 3.1.1

##### **mesoscopic shape**

description of shape at the observation scale for an individual multiwall carbon nanotube (MWCNT)

Note 1 to entry: Mesoscopic shape factors describe the average size and shape of individual MWCNTs, while “macroscopic” describes the shape and size of MWCNT aggregates or agglomerates. “Atomic scale resolution” describes the shape of an MWCNT at the atomic level (see [Figure 1](#)).

Note 2 to entry: See Reference [\[4\]](#).



NOTE SOURCE: 2010 ACS

Figure 1 — Shape of MWCNTs at various scales

3.1.2

**regular shape**

⟨MWCNTs⟩ property of having a regular pattern along the tube axis

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Note 1 to entry: Correlations in the direction of the tangent show a periodical shape for MWCNTs of regular shape. Both straight and coil-shaped MWCNTs are typically classified as MWCNTs of regular shape.

3.1.3

**random shape**

⟨MWCNTs⟩ property of having static or permanent bend points distributed randomly (Gaussian) along their tube axis

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3.1.4

**static bending persistence length**

**SBPL**

$l_{sp}$   
maximum straight length without static bending

3.1.5

**contour length**

$L$   
total length of an MWCNT along its axis

3.1.6

**weighted average contour length**

$\bar{L}_w$   
average of contour length which is assigned a weight

3.1.7

**end-to-end distance**

$R$   
straight distance between the two ends of an MWCNT

3.1.8

**bending ratio**

$D_b$   
ratio between mean-squared end-to-end distance and squared contour length



**3.1.9****intrinsic viscosity**[ $\eta$ ]

description of an MWCNT's contribution to the viscosity of MWCNT dispersion

**3.2 Abbreviated terms**

CVD	chemical vapour deposition
DDLS	depolarized dynamic light scattering
DLS	dynamic light scattering
DMF	dimethylformamide
SBPL	static bending persistence length
SEM	scanning electron microscopy
TEM	transmission electron microscopy

**4 Sample preparation methods****4.1 Ball mill cutting**

Place 200 mg of MWCNTs and 20 ml of ethanol and zirconia balls (5,2 mm) into a zirconia pot (150 ml) and ball mill 500 r/min for 2 h. (standards.iteh.ai)

Pour the ball-milled MWCNT dispersion from the zirconia pot into a 50 ml conical centrifuge tube at 5 000 r/min.

Centrifuge the ball-milled MWCNT dispersion to separate the MWCNTs and then freeze-dry the separated MWCNTs for 24 h. Dry the MWCNTs at 300 °C for 30 min while exposed to air to remove unwanted volatile components.

Grind the dried MWCNTs by pestle and mortar.

NOTE When higher r/min and longer ball-milling time are applied than those described here, the structure of MWCNTs might be destroyed.

**4.2 Dispersion method**

Disperse 0,02 g of milled MWCNTs in 200 ml dimethylformamide (DMF) using an ultra-sonicator at 40 W for 3 h. Pour the MWCNT dispersion into a 50 ml conical centrifuge tube and centrifuge at 3 000 r/min for 30 min. Filter the dispersion with a paper filter (pore size 10  $\mu$ m) to eliminate any non-dispersed parts that might remain.

NOTE DMF is the best solvent for CNT dispersion (see Reference [4,5]).

**4.3 Sample preparation for SEM**

Use additional DMF to dilute the MWCNT dispersion to 10 $\times$ . Drop 1 ml of the 10 $\times$  dispersion onto a 0,02  $\mu$ m ceramic filter and filter it under vacuum. Dry the ceramic filter, containing the MWCNTs, at 60 °C for 24 h.

**4.4 Alternative sample preparation method**

Following the methods in order (4.1, 4.2 and 4.3) is recommended for Method 1 (see 5.1.2.1) and Method 3 (see 5.1.2.3). As-synthesized MWCNTs can be used for Method 2 (see 5.1.2.2).

## 5 Experimental procedure

### 5.1 Measurements of the SBPL using SEM

#### 5.1.1 SEM

##### 5.1.1.1 General

High-resolution SEM images allow closely spaced features to be examined at a high magnification.

##### 5.1.1.2 Preparing SEM images

Cut the ceramic filter containing the MWCNTs into small pieces and place on a sample holder, to which conductive tape is applied. Dry the sample holder under vacuum at 40 °C for 1 h. Sputter coat the dried sample with iridium for 1 min. Gold, platinum, or carbon may be used if an iridium source is not available. Take three or more SEM images at a magnification of 10 000×. Take three or more representative high-resolution images at 20 000×. This procedure is recommended for Method 1 (5.1.2.1) and Method 3 (5.1.2.3).

Alternatively, place an as-synthesized MWCNT on a sample holder, to which conductive tape is applied. Dry the sample holder under vacuum at 40 °C for 1 h. Sputter coat the dried sample with iridium for 1 min. Gold or platinum may be used if an iridium source is not available. Take three or more SEM images at a magnification of 10 000×. Take three or more representative high-resolution images at 20 000×. This procedure is recommended for Method 2 (see 5.1.2.2).

NOTE 1 Sputter coating for more than 1 min can cause a slight change in the bending of the MWCNT.

### 5.1.2 Measurement methods for the SBPL

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#### 5.1.2.1 Method 1

From the SEM images, determine the contour lengths and end-to-end distances of at least 100 different individual MWCNTs. Classify the data using an interval of 100 nm for contour length. For each contour length range, calculate the mean-squared end-to-end distance.

Obtain the bending ratio for each contour length range by dividing the mean-squared end-to-end distance by the squared average contour length [see [Formula \(A.3\)](#)]. When the contour length is greater than 1µm, the value of contour length from the top view image may be underestimated by up to 15 %.<sup>[1]</sup> When more accurate values are required, measure the contour length and end-to-end distance using a 3D image, which can be obtained by several side view images.<sup>[1]</sup>

Plot the bending ratio with respect to the reciprocal contour length, measure the gradient and determine the SBPL using [Formula \(A.4\)](#). When the linear relationship between bending ratio and reciprocal contour length reaches the asymptotic limit, the resulting slope equals two times the SBPL.

NOTE 1 For MWCNTs of random shape, the end-to-end distance varies at constant contour length.<sup>[1]</sup> Therefore, various values of end-to-end distance could be measured for each contour length range. The distribution of end-to-end distance of MWCNT is Gaussian for each contour length range when MWCNTs are of random shape. To obtain the mean-squared end-to-end distance, the mean value of the squared end-to-end distance is calculated.

NOTE 2 Because well-dispersed MWCNTs are filtered prior to SEM imaging, 100 MWCNTs are sufficiently representative of the shape of the MWCNTs in the sample. This is supported by DLS and DDLS measurements as well as intrinsic viscosity measurements.<sup>[1]</sup> An approximate value for the SBPL can be obtained using Method 2 or Method 3.

### 5.1.2.2 Method 2

Measure the radius of curvature of at least 100 individual tubes from the SEM images of as-synthesized MWCNTs, then calculate the mean value of the radius of curvature. This mean radius is approximately equal to the value of SBPL.

### 5.1.2.3 Method 3

From the SEM image, select at least 10 MWCNTs with a contour length in the range of  $2,0 \mu\text{m} \pm 0,2 \mu\text{m}$ . Measure the end-to-end distance of each MWCNT. The approximate value of SBPL can be obtained from the mean-squared end-to-end distance and the squared average contour length [see [Formula \(A.3\)](#) and [Formula \(A.4\)](#)].

NOTE 1 Method 1 is the most accurate method but it is time consuming. The SBPL estimated by Method 2 has up to 20 % deviation compared to Method 1 (Method 2 has a tendency to underestimate the SBPL). The SBPL estimated by Method 3 has up to 100 % deviation compared to the value obtained by Method 1. The order of magnitude of SBPL has consequences for many applications such as transparent conductive film, electrode and polymer composites.

NOTE 2 The values of SBPL obtained by Method 1, Method 2, and Method 3 can be confirmed by the viscometry method ([Annex B](#)) and/or the light scattering method ([Annex C](#)).

## 5.2 Measuring inner and outer diameters of MWCNTs using TEM

Place a droplet of the diluted MWCNT/DMF dispersion onto a carbon-coated copper grid. Dry the grid at  $60 \text{ }^\circ\text{C}$  for 24 h. Take TEM images at  $10\,000\times$  magnification. Take three or more high-resolution images at  $1\,000\,000\times$  to  $3\,000\,000\times$  of the MWCNT.

In order to obtain averages, measure the inner and outer diameters at not less than three different positions along the axis for at least 10 different MWCNTs. At least 30 total measurements are required.

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## 6 Test report

The test report shall contain the following information (see [Annex D](#)):

- a) a full description of the sample preparation method(s) used;
- b) average inner and outer diameter (m);
- c) method used to determine SBPL;
- d) SBPL (m);
- e) all information necessary for evaluating the SBPL.

The test report may also include information relating to weighted average contour length and bending ratio (optional).